

INRF **BiON**

WORKSHOPS

Come join us to “Engineer the Microworld”



INRF & Bion are offering three different workshops:
Lithography, Metal Deposition & Reactive Ion Etching.

The purpose of these workshops is to give you more familiarity with the tools and their capabilities and to give you the best end result that the tool is able to perform.

These workshops will consist of some lectures but mostly hands on.

You need to register and to be an INRF or BiON user in order to attend the following workshops.

TOPICS:

■ Lithography

Overview of the MA6, MA56 and their various functions. Also covers flood exposure and photo resist application onto various substrates and the proper use of developing.

■ Metal Deposition

Overview of Deposition tools depositing of different materials using different types of tools such as E-beam, thermal evaporator and sputtering systems, and the pros and cons and basic operation of these tools.

■ Reactive Ion Etching

Overview of the different reactive Ion etchers the facility has. First is the Plasma Therm that is set up for metal etch, then Trion which is configured for RIE and ICP for Nitrite and Oxide processes, The STS which is DRIE, is dedicated for silicon etch only. The SPTS which is set up for various types of glass etches. We will also cover different mask methods for these tools.



**COURSE BEGIN
IN APRIL**

**LOCATION
2220
Engineering
Gateway**

To register for a workshop, visit www.inrf.uci.edu/workshops. For any questions, contact Dexter Humphrey at dexterh@uci.edu